Title: **JP08338546A2: PRESSURE TYPE FLOW CONTROL DEVICE**

Derwent Title: Pressure type flow rate control appts. used in semiconductor and chemical manufacturing plants - adjusts orifice upstream side pressure by opening and closing control valve, to control orifice downstream side flow rate [Derwent Record]

Country: **JP** Japan
Kind: **A** (See also: JP03291161B2)

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Published / Filed: **1996-12-24** / 1995-06-12

Application Number: **JP1995000144722**

IPC Code: **F16K 17/22;**

Priority Number: 1995-06-12 **JP1995000144722**

Abstract: PURPOSE: To heighten the control accuracy of a flow control device and to reduce the size and cost of the device.

CONSTITUTION: A pressure type flow control device is adapted to control the flow of a fluid by keeping the orifice upstream side pressure about two or more times as large as the downstream side pressure. The flow control device comprises an orifice 5, a control valve 2 disposed on the upstream side thereof, a pressure detecting device 3 disposed between the control valve 2 and the orifice 5, and an arithmetic control device 6 for computing the flow from the detected pressure P1 of the pressure detecting device 3 as Qc=KP1 (wherein K is a constant) and outputting a difference between a flow command signal Qs and the computed flow Qc as a control signal Qy to the driving part of the control valve 2. The pressure P1 is regulated by opening and closing the control valve 2 to control the downstream side flow of the orifice 5.

INPADOC Legal Status: None **Get Now:** Family Legal Status Report

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Family: Show 14 known family members

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References:

PDF	Patent	Pub.Date	Inventor	Assignee	Title
	US6450190	2002-09-17	Ohmi; Tadahiro	Ohmi; Tadahiro	Method of detecting abn flow rate in pressure-typ
	US6158679	2000-12-12	Ohmi; Tadahiro	Fujikin Incorporated	Orifice for pressure type control unit and process manufacturing orifice

Other Abstract Info: DERABS G97-036302

(19) JAPANESE PATENT OFFICE

PATENT ABSTRACTS OF JAPAN

(11) Publication number: **08338546 A**
(43) Date of publication of application: **24.12.1996**

(51) Int. Cl **F16K 17/22**

(21) Application number: **07144722**
(22) Date of filing: **12.06.1995**

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